

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Van Beek, *et al.* Docket No.: EPC-019  
Serial No.: 10/578,026 Conf. No.: 4725  
Art Unit: 2829 Examiner: Karen M. Kusumakar  
Filed: March 13, 2007  
For: Method of Manufacturing a MEMS Device and MEMS Device

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed September 8, 2009. Please amend the above-referenced application as follows.